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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO	
09/836,065 04/16/2001		Janevoot Naksrikram	P1310	5713	
75	90 12/01/2004	EXAMINER			
Farjami & Far		CHAUDRY, MUJTABA M			
26522 La Alamo Suite 360	eda Avenue		ART UNIT	PAPER NUMBER	
Mission Viejo, CA 92691			2133		

DATE MAILED: 12/01/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application	n No.	Applicant(s)				
Office Action Summary		09/836,06	5	NAKSRIKRAM ET A	L.			
		Examiner		Art Unit				
		Mujtaba K	Chaudry	2133				
Period fo	The MAILING DATE of this communic or Reply	cation appears on the	cover sheet with the	e correspondence addr	ess			
THE - Exte after - If the - If NO - Failt Any	ORTENED STATUTORY PERIOD FO MAILING DATE OF THIS COMMUNIOnsions of time may be available under the provisions of SIX (6) MONTHS from the mailing date of this commit of period for reply specified above is less than thirty (30 period for reply is specified above, the maximum stature to reply within the set or extended period for reply vireply received by the Office later than three months afted patent term adjustment. See 37 CFR 1.704(b).	CATION. of 37 CFR 1.136(a). In no eve unication. l) days, a reply within the stat tutory period will apply and wi will, by statute, cause the app	ent, however, may a reply be utory minimum of thirty (30) o Il expire SIX (6) MONTHS for ication to become ABANDO	timely filed  lays will be considered timely.  om the mailing date of this common NED (35 U.S.C. § 133).	munication.			
Status								
1)  🛛	Responsive to communication(s) file	d on <i>06 August 2004</i>						
2a)⊠	•	tb)☐ This action is n						
3)□	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.							
Disposit	ion of Claims							
5)□ 6)⊠ 7)□	Claim(s) 1-18 is/are pending in the a 4a) Of the above claim(s) is/are Claim(s) is/are allowed. Claim(s) 1-18 is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restrict	re withdrawn from co	·					
Applicat	ion Papers							
9)□	The specification is objected to by the	e Examiner.						
10)	The drawing(s) filed on is/are:	a) accepted or b)	objected to by th	e Examiner.				
	Applicant may not request that any object	<del>-</del>	•	• •				
11)	Replacement drawing sheet(s) including The oath or declaration is objected to							
Priority	under 35 U.S.C. § 119	•						
a)	Acknowledgment is made of a claim to All b) Some * c) None of:  1. Certified copies of the priority of the priority of the certified copies of the priority of the certified copies of the certified copies of application from the Internation See the attached detailed Office actions	documents have bee documents have bee of the priority documental Bureau (PCT Rul	n received. In received in Applicents have been rece e 17.2(a)).	ation No ived in this National S	tage			
Attachme	nt(s)		_					
	ce of References Cited (PTO-892)	TO 048)	4) Interview Summ Paper No(s)/Mai					
3) 🔲 Info	ce of Draftsperson's Patent Drawing Review (Prmation Disclosure Statement(s) (PTO-1449 or er No(s)/Mail Date			al Patent Application (PTO-1	152)			

**DETAILED ACTION** 

**Drawings** 

The insertion a "Prior Art" label to Figure 1 is accepted. However, this application, filed under

former 37 CFR 1.60, lacks formal drawings. The informal drawings filed in this application are

acceptable for examination purposes. New corrected drawings are required. Applicant is advised

to employ the services of a competent patent draftsperson outside the Office, as the U.S. Patent

and Trademark Office no longer prepares new drawings. The corrected drawings are required in

reply to the Office action to avoid abandonment of the application. The requirement for corrected

drawings will not be held in abeyance.

Specification

The corrected or substitute specification were received on August 06, 2004. The specification is

accepted.

Response to Amendment

Applicant's arguments/amendments with respect to amended claims 1-3, 5, 8, 12, 14 and 17 and

original claims 4, 6, 7, 9, 11, 13, 15, 16 and 18 filed August 06, 2004 have been fully considered

but are not persuasive. The Examiner would like to point out that this action is made final (See

MPEP 706.07a).

Applicant contends, "...the prior arts of record (Noguchi and Kobayashi) do not teach a

method for testing a semiconductor device having a first sector of a first sector type memory and

a second sector of a second sector type memory size." The Examiner respectfully disagrees. Noguchi teaches (col. 7 and Figure 14) a flow chart showing the erasing operation of this nonvolatile semiconductor memory device. First, at the stage of initializing, a program high voltage Vpp is applied to the instruction port controller 2 to render the instruction port controller 2 operative (a step S2). Then, specific data (00H) is programmed for all bytes, a step S4. This data programming is made in order to bring each memory cell into a write state and set the threshold voltage of each memory cell to be substantially equal. In addition, each counter is preset to a predetermined initial value (a step S6). This counter includes a counter for counting the number of time CUMTEW of the increase of an erase pulse width TEW, and a counter for counting the number of times PLSCNT by which erase pulses are generated. An address is set to 0. Then, an erase setup instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S8), and an erase instruction is subsequently written into the instruction port controller 2 (a step S10). An erasing with respect to all the memory cells is executed in accordance with the writing of the erase instruction (a step S12). After a predetermined time period has passed, it is determined that the erasing of the memory cells is completed, and an erase verify instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S14). In accordance with this erase verify instruction, an erase verify voltage is generated from the erase/program verification generator 9 and then transmitted via the X decoder 12 onto a selected word line in the memory cell array (a step S16). When a predetermined time period has passed (time T2), data reading is carried out (a step S18). If the read data is an erased data, then the data is "1". If the read data is an unerased data, then the data is "0". A determination is made as to whether this

data is in the erased state or not in accordance with its value (a step S20). If the data indicates the unerased state, then an erase pulse width to be applied to erase the data is incremented by a predetermined value, and this incremented erase pulse width information is stored in the TEW counter (a step S22). A determination is first made as to whether the erase pulse width stored in the TEW counter reaches a maximum limit value, and subsequently, a determination is made as to whether the number by which the erase pulses are applied reaches a predetermined value (64 times) (a step S24). When the erase pulse application number PLSCNT reaches the predetermined value (64 times), it is determined that no erasing is allowed for that memory cell any more, and an erase error is stored (a step S26). When the erase pulse application number PLSCNT does not reach the predetermined value in the step S24, the processing returns to the step S8, in which the writing and erasing operation by the erase setup instruction and the erase instruction is carried out. The Examiner would like to point out that Noguchi teaches to test a Flash memory which is also a non-volatile memory. By definition, a Flash memory is an erasable programmable read-only memory in which clearing can be performed only on block or the entire array. Therefore, Noguchi teaches a method for testing a semiconductor device having a first sector of a first sector type memory and a second sector of a second sector type memory size as stated in the present application.

## Claim Rejections - 35 USC § 103

The factual inquiries set forth in *Graham* v. *John Deere Co.*, 383 U.S. 1, 148 USPQ 459 (1966), that are applied for establishing a background for determining obviousness under 35 U.S.C. 103(a) are summarized as follows:

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- 1. Determining the scope and contents of the prior art.
- 2. Ascertaining the differences between the prior art and the claims at issue.
- 3. Resolving the level of ordinary skill in the pertinent art.
- 4. Considering objective evidence present in the application indicating obviousness or nonobviousness.

Claims 1-18 are rejected under 35 U.S.C. 103(a) as being unpatentable over Noguchi (USPN 5343434) further in view of Kobayashi et al. (USPN 5646948). From previous office action:

As per claims 1 and 10, Noguchi substantially teaches (title and abstract) a method and apparatus for performing erase testing on a semiconductor device. Noguchi teaches a memory device in a bare chip state which is determined as fail by over erasing during a test at a wafer level, information indicating the presence of an over-erased memory cell is stored in a nonvolatile and readable manner into an identification memory circuit, and then memory cells in a memory cell array are restored to an erase state of an electrically neutral state by irradiation with an energy beam such as ultraviolet rays. A chip erased by the energy beam such as ultraviolet rays is assembled as an OTPROM (one-time programmable read only memory) and tested. At that time, a writing/erasing control circuit for controlling data writing into and data erasing in the memory cells is brought into an operation-inhibited state in accordance with the information stored in the memory circuit. It is possible to reduce the rate at which fail products are produced by use of a flash memory which is determined as fail because of the presence of an over-erased memory cell as a one-time programmable memory device. Furthermore, Noguchi teaches (Figure 14) the erasing operation of a nonvolatile semiconductor memory device. First, at the stage of initializing, a program high voltage Vpp is applied to the instruction port controller 2 to render the instruction port controller 2 operative (a step S2). Then, specific data (00H) is programmed for all bytes (data input/output is carried out in the units of byte and

erasing is carried out also in the units of byte) (a step S4). This data programming is made in order to bring each memory cell into a write state and set the threshold voltage of each memory cell to be substantially equal. The Examiner would like to point out that this step is analogous to establishing a first test limit as stated in the present application. In addition, each counter is preset to a predetermined initial value (a step S6). This counter includes a counter for counting the number of time CUMTEW of the increase of an erase pulse width TEW, and a counter for counting the number of times PLSCNT by which erase pulses are generated. An address is set to 0. Then, an erase setup instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S8), and an erase instruction is subsequently written into the instruction port controller 2 (a step S10). An erasing with respect to all the memory cells is executed in accordance with the writing of the erase instruction (a step S12). After a predetermined time period has passed, it is determined that the erasing of the memory cells is completed, and an erase verify instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S14). In accordance with this erase verify instruction, an erase verify voltage is generated from the erase/program verification generator 9 and then transmitted via the X decoder 12 onto a selected word line in the memory cell array (a step S16). When a predetermined time period has passed (time T2), data reading is carried out (a step S18). If the read data is an erased data, then the data is "1". If the read data is an unerased data, then the data is "0". A determination is made as to whether this data is in the erased state or not in accordance with its value (a step S20). If the data indicates the unerased state, then an erase pulse width to be applied to erase the data is incremented by a predetermined value, and this incremented erase pulse width information is stored in the TEW counter (a

step S22). A determination is first made as to whether the erase pulse width stored in the TEW counter reaches a maximum limit value, and subsequently, a determination is made as to whether the number by which the erase pulses are applied reaches a predetermined value (64) times) (a step S24). When the erase pulse application number PLSCNT reaches the predetermined value (64 times), it is determined that no erasing is allowed for that memory cell any more, and an erase error is stored (a step S26). When the erase pulse application number PLSCNT does not reach the predetermined value in the step S24, the processing returns to the step S8, in which the writing and erasing operation by the erase setup instruction and the erase instruction is carried out. Noguchi does not explicitly teach to have a first sector of a first sector type and a second sector with a second sector type as stated in the present application. However, Kobayashi et al. (herein after: Kobayashi), in an analogous art, substantially teaches (title and abstract) a method and apparatus for testing a plurality of semiconductor memories in parallel. Kobayashi teaches a test data pattern, an address pattern, and a control signal are supplied from a pattern generator to a test memory. Data read from the test memory is compared with expected data by an XOR gate. When they match, a compared result that represents pass is output. When they mismatch, a compared result that represents fail is output. A match signal WC detected by the XOR gate is held in a register. The register outputs an inhibition signal to an inhibition gate of the test memory. Thus, a write enable signal WE is inhibited from being supplied to the test memory. In addition, the inhibition signal is supplied to a compared result inhibition gate. The compared result inhibition gate causes the compared result to be passed and prevents the test memory from being excessively written. Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to incorporate the

multiple memories of Kobayashi with the testing apparatus of Noguchi. This modification would have been obvious to one of ordinary skill in the art because one of ordinary skill in the art would have recognized that by applying the testing routine taught by Noguchi with multiple memory types would reduce overall testing time.

As per claims 2-6 and 11-15, Noguchi substantially teaches, in view of above rejections, (Figure 1) a block diagram showing an overall structure of a nonvolatile semiconductor memory device according to one embodiment. FIG. 1 shows a structure of a flash memory in which all memory cells in a memory cell array 13 are brought into an erase state at the same time. This structure corresponds to the structure of the conventional nonvolatile semiconductor memory device shown in FIG. 12. The structure of this memory device is applicable not only to the flash memory in which all memory cells of the memory cell array 13 are erased at the same time but also to a nonvolatile semiconductor memory device of the type in which erasing is made in units of a sector, a word line or a byte. Corresponding portions of the memory device of FIG. 1 to those of the conventional nonvolatile semiconductor memory device shown in FIG. 12 are denoted with the same reference numerals. Moreover, in an erasing operation, the same effects as those provided in the foregoing embodiment can be obtained even in a structure in which not every memory cell is erased at the same time but only memory cells to be programmed are erased. That is, the same effects as those provided in the foregoing embodiment can be obtained even in a nonvolatile semiconductor memory device in which data erasing is carried out in the units of word line, the units of byte or the units of sector. Furthermore, an erase setup instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S8), and an erase instruction is subsequently written into the instruction port

controller 2 (a step S10). An erasing with respect to all the memory cells is executed in accordance with the writing of the erase instruction (a step S12). After a predetermined time period has passed, it is determined that the erasing of the memory cells is completed, and an erase verify instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S14). In accordance with this erase verify instruction, an erase verify voltage is generated from the erase/program verification generator 9 and then transmitted via the X decoder 12 onto a selected word line in the memory cell array (a step S16). When a predetermined time period has passed (time T2), data reading is carried out (a step S18).

As per claims 7-9 and 16-18, Noguchi substantially teaches, in view of above rejections, the erasing operation of a nonvolatile semiconductor memory device. First, at the stage of initializing, a program high voltage Vpp is applied to the instruction port controller 2 to render the instruction port controller 2 operative (a step S2). Then, specific data (00H) is programmed for all bytes (data input/output is carried out in the units of byte and erasing is carried out also in the units of byte) (a step S4). This data programming is made in order to bring each memory cell into a write state and set the threshold voltage of each memory cell to be substantially equal. The Examiner would like to point out that this step is analogous to establishing a first test limit as stated in the present application. In addition, each counter is preset to a predetermined initial value (a step S6). This counter includes a counter for counting the number of time CUMTEW of the increase of an erase pulses width TEW, and a counter for counting the number of times PLSCNT by which erase pulses are generated. An address is set to 0. Then, an erase setup instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S8), and an erase instruction is subsequently written into the

instruction port controller 2 (a step S10). An erasing with respect to all the memory cells is executed in accordance with the writing of the erase instruction (a step S12). After a predetermined time period has passed, it is determined that the erasing of the memory cells is completed, and an erase verify instruction is written into the instruction port controller 2 (the status register 235 and the instruction register 237) (a step S14). In accordance with this erase verify instruction, an erase verify voltage is generated from the erase/program verification generator 9 and then transmitted via the X decoder 12 onto a selected word line in the memory cell array (a step S16). When a predetermined time period has passed (time T2), data reading is carried out (a step S18). If the read data is an erased data, then the data is "1". If the read data is an unerased data, then the data is "0". A determination is made as to whether this data is in the erased state or not in accordance with its value (a step S20). If the data indicates the unerased state, then an erase pulse width to be applied to erase the data is incremented by a predetermined value, and this incremented erase pulse width information is stored in the TEW counter (a step S22). A determination is first made as to whether the erase pulse width stored in the TEW counter reaches a maximum limit value, and subsequently, a determination is made as to whether the number by which the erase pulses are applied reaches a predetermined value (64) times) (a step S24). When the erase pulse application number PLSCNT reaches the predetermined value (64 times), it is determined that no erasing is allowed for that memory cell any more, and an erase error is stored (a step S26). When the erase pulse application number PLSCNT does not reach the predetermined value in the step S24, the processing returns to the step S8, in which the writing and erasing operation by the erase setup instruction and the erase instruction is carried out.

The Examiner disagrees with the Applicant and maintains rejections with respect to amended claims 1-3, 5, 8, 12, 14 and 17 and original claims 4, 6, 7, 9, 11, 13, 15, 16 and 18. All arguments have been considered. It is the Examiner's conclusion that amended claims 1-3, 5, 8, 12, 14 and 17 and original claims 4, 6, 7, 9, 11, 13, 15, 16 and 18 are not patentably distinct or non-obvious over the prior art of record. See prior office action above.

## Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

Any inquiries concerning this communication should be directed to the examiner,

Mujtaba Chaudry who may be reached at 571-272-3817. The examiner may normally be reached

Mon – Thur 6:30 am to 4:30 pm.

If attempts to reach the examiner by telephone are unsuccessful, please contact the examiner's supervisor, Albert DeCady at 571-272-3819.

Mujtaba Chaudry

Art Unit 2 33 November 16, 2004

SUPERVISORY PATENT EXAMINER
TECHNOLOGY CENTER 2100